

Japan Gases & Facilities Committee Meeting Summary and Minutes

SEMI Japan Spring 2014 Meetings
Friday, April, 4, 2014, 15:00-17:00
SEMI Japan, Tokyo, Japan

Next Committee Meeting

SEMI Japan Standards Summer 2014 Meetings
Friday, July 4, 2014, 15:00-17:00
SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees

Co-Chairs: Hiromichi Enami (Hitachi High Technologies), Isao Suzuki (MKS Japan)

SEMI Staff: Naoko Tejima (SEMI Japan)

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Hitachi High Technologies	Enami	Hiromichi	Tokyo Electron Yamanashi	Moriya	Shuji
Swagelok	Ishida	Noritsugu	Tokyo Electron Tohoku	Okabe	Tsuneyuki
Flow Techno Service	Ishihara	Seiji	Omron	Ogawa	Makoto
HORIBA STEC	Isobe	Yasuhiro	HORIBA STEC	Shimizu	Tetsuo
ITW Japan	Kashiwazaki	Hokuto	MKS Japan	Suzuki	Isao
Fujikin	Machii	Yoshifumi	SEMI Japan	Naoko	Tejima
ACE	Mihira	Hiroshi			

** alphabetical order by last name*

Table 2 Leadership Changes

None.

Table 3 Ballot Results

Passed ballots and line items will be forwarded to the ISC Audit & Review Subcommittee for procedural review.

Failed ballots and line items were returned to the originating task forces for re-work and re-balloting.

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
5686	Reapproval of SEMI F80-0309, Test Method for Determination of Gas Change/Purge Efficiency of Gas Delivery System	Passed as balloted

Table 4 Authorized Ballots

None.

Table 5 Authorized Activities

None.

Table 6 New Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
G+F140404-01	SEMI staff	To forward adjudication result of Doc.#5636 to the ISC A&R Subcommittee for procedural review.
G+F140404-02	SEMI staff	To contact with the negative voter and to explain the ballot review result of the Task Force and the Committee. (Doc.#5636)
G+F140404-03	SEMI Staff	To check whether there are some documents for 5-year-review procedure.
G+F140404-04	Standardization of Live Gas Flow Rate SG	To survey about the ideal way to measure the Live Gas Flow Rate to the Mass Flow Manufacturers.
G+F140404-05	Standardization of Live Gas Flow Rate SG	To make the meeting minutes in English to share the information with the Facilities and Gases NA TC Chapter.
G+F140404-06	SEMI Staff	To inform to the Facilities and Gases NA TC Chapter to stop the discussion about the standardization of the specific heat value and the calibration conditions with SG meeting minutes.

1 Welcome, Reminders and Introductions

Hiroichi Enami, committee co-chair, called the meeting to order at 15:00. Self-introductions were made followed by the agenda review.

2 Required Meeting Elements

The meeting reminders on program membership requirement, antitrust issues, intellectual property issues and international effective meeting guidelines, were reviewed by SEMI staff, Naoko Tejima.

3 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on December 4, 2013.

Motion: To approve the minutes of the previous meeting as written.

By / 2nd: Isao Suzuki (MKS Japan) / Seiji Ishihara, (Flow Techno Service)

Discussion: None

Vote: 11 in favor and 0 opposed. **Motion passed.**

Attachment: 01_JA_G+F_Previous_Mtg_Minutes_140404

4 SEMI Staff Report

Naoko Tejima gave the SEMI staff report. This report included SEMI Global 2014 Calendar of Events, Global Standards Meeting Schedule, North America Standards Spring Meetings 2014 Schedule, Critical Dates for SEMI Standards Ballots, SEMI Standards Publications, A&R Ballot Review Report, and Contact Information.

Attachment: 02_SEMI_Staff_Report_140404

5 Liaison Reports

5.1 North America Facilities and Gases Committee

No report was provided.

5.2 Europe Gases and Liquid Chemicals Committee

Naoko Tejima briefly reported for the Europe Gases & Liquid Chemicals Committee. This report included Leadership, Current Committee Organization, Meeting Information, Ballot Results from Oct 2013 TC Meeting, New SNARFs from Oct 2013 TC Meeting, Existing SNARFs, Upcoming Ballots for 2014, Task Force Reports and Contact Information.

Attachment: 03_EU_Gases_&_Liquid_Chemicals_Report_140404

5.3 Korea Facilities Committee

No report was provided.

6 Ballot Review

6.1 Doc.#5686, Reapproval of SEMI F80-0309, Test Method for Determination of Gas Change/Purge Efficiency of Gas Delivery System

This document passed committee review with editorial changes and will be forwarded to the ISC A&R SC for procedural review. One reject was voted, but it disposed that the negative was related and not persuasive.

Action Item: SEMI staff to forward adjudication result of Doc.#5636 to the ISC A&R Subcommittee for procedural review.

Action Item: SEMI staff to contact with the negative voter and to explain the ballot review result of the Task Force and the Committee.

Attachment: 04_Ballot_Report_for_5686_140404

7 Task Force Reports

7.1 F1 Revision Task Force

Yoshifumi Machii reported for the F1 Revision Task Force that there were not particular activities.

7.2 Gas Panel and Metal Seal Test Methods Task Force

Shuji Moriya reported for the Gas Panel and Metal Seal Test Methods Task Force that there were not particular activities.

7.3 5-year-review Task Force

Yoshifumi Machii reported for the 5-year-review Task Force. Of note:

- Doc.#5686, Reapproval of SEMI F80-0309, Test Method for Determination of Gas Change/Purge Efficiency of Gas Delivery System, passed committee review as previously discussed. (See 6.1).

Action Item: SEMI Staff to check whether there are some documents for 5-year-review procedure.

7.4 Standardization of Live Gas Flow Rate Study Group

Shuji Moriya reported for the Standardization of Live Gas Flow Rate Study Group. The Study Group met earlier in the day. Of note:

- Shared and discussed the result of the survey about calibration of Live Gas Flow Rate which was made to Mass Flow Manufacturers. (the 2nd survey)
- The standardization of the specific heat value and the calibration conditions seem to be difficult, and even if they could be standardized, the standards related to the actual flow rate would not be included.
- As result, SG has decided to stop the discussion about the standardization of the specific heat value and the calibration conditions.
- At the next step, SG will discuss whether the actual measurement of the live Gas flow rate could be standardized.
- SG will request to AIST and the member of JCSS to make the presentation about the standardization of the live Gas flow rate.

Action Item: SG to survey about the ideal way to measure the Live Gas Flow Rate to the Mass Flow Manufacturers.

Action Item: SG to make the meeting minutes in English to share the information with the Facilities and Gases NA TC Chapter.

Action Item: SEMI staff to inform to stop the discussion about the standardization of the specific heat value and the calibration conditions with SG meeting minutes.

8 Old Business

8.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

Table 7 Previous Meeting Actions Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
G+F130927-01	SEMI Staff	To prepare SNARF and SEMI F80 Reapproval ballot for Cycle 1, 2014. ... Close
G+F131204-01	NA Surface Mount Sandwich Component Dimensions TF	To send some information about Doc. 5596, "New Standard: Guide for the Development of Dimensional Standards for "Sandwich" Surface Mount Components", if they have. ... Close
G+F131204-02	Standardization of Live Gas Flow Rate SG	To make the meeting minutes and send it to the NA Committee. ... Close
G+F130927-03	Standardization of Live Gas Flow Rate SG	To resurvey about calibration of Live Gas Flow Rate will be made to Mass Flow Manufacturers, focusing on the item which could be candidates to be standardized. ... Close
G+F131204-04	Standardization of Live Gas Flow Rate SG	To ask some comments and opinions to be standardized the specific heat value to NA Gas Specification TF and Europe Gases & Liquid Chemicals Committee. ... Close

9 New Business

9.1 The Current Situation of the Sensor Bus; "The Next Generation SAN which Transform the Control of Semiconductor Manufacturing Equipment" was presented by Makoto Ogawa, Omron.

9.2 Report related to the EHS & 450mm; "The Current Situation of the Environment of the World Wide Semiconductor Manufacturing, and its impact and handling" was presented by Hiromichi Enami, Hitachi High Technologies

10 Action Item Review

10.1 New Action Items

Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

11 Next Meeting and Adjournment

The next meeting of the Japan Gases & Facilities Committee is scheduled for Friday, July 4, 2014, 15:00-17:00, at SEMI Japan, Tokyo, Japan.

Prior to the Committee meeting, SG will be held on the same day.

Respectfully submitted by:
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Minutes approved by:

Hikomichi Enami (Hitachi High Technologies), Co-chairs	May 20, 2014
Isao Suzuki (MKS Japan), Co-chairs	May 20, 2014

Table 8 Index of Available Attachments #1

#	<i>Title</i>
1	JA_G+F_Previous_Mtg_Minutes_140404
2	SEMI_Staff_Report_140404
3	EU_Gases_&_Liquid_Chemicals_Report_140404
4	Ballot_Report_for_5686_140404

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Naoko Tejima at the contact information above.